Infrared Spectroscopic Study of the Adsorption and Dissociation of CH₂Cl₂ on Pd/SiO₂

Generation of CH₂ Species

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The adsorption and dissociation of CH₂Cl₂ have been investigated by means of infrared spectroscopy combined with mass spectrometry. CH₂Cl₂ adsorbs molecularly on Pd/SiO₂ at low temperature (193-213 K) and interacts strongly with the OH groups of silica to form H-bridge-bonded methylene halide. This is exhibited by a significant attenuation of the 3744 cm⁻¹ band exhibited by silica and by the development of a broad spectral feature at 3662 cm⁻¹. The dissociation of CH₂Cl₂ was observed at 233-243 K. The primary product of dissociation, CH₂, was characterized by absorption bands at 2984 and 2907 cm⁻¹. The CH₂ species dimerized into C₂H₄ above 263 K. A fraction of ethylene desorbed, while another fraction was transformed into ethylidyne. The latter compound is characterized by absorption bands at 2922 and 2857 cm⁻¹. By means of mass spectrometry C₂H₄ and HCl were identified in the desorbing gases at 250-330 K. Decomposition of CH₂Cl₂ occurred above 350 K yielding C₂H₄, CH₄, HCl, and H₂O. Some exploratory measurements were also performed with CH₂I₂. © 1995 Academic Press, Inc.

1. INTRODUCTION

This study is a continuation of our research program aiming to produce CH_x fragments on Pd catalysts. In the frame of this program we examined first the adsorption and dissociation of CH_3X (X, halide) (1), CH_2X_2 (2), and C_2H_5X (3) on the Pd(100) surface under UHV conditions. We found that iodine compounds are more suitable to generate CH_x fragments than materials containing chloride. In addition, illumination of adsorbed layers markedly enhanced the extent of dissociation and produced CH_x fragments in a larger quantity even at 85–90 K, far below the temperature of their secondary thermal reactions. As an extension of this work to actual catalysts, the adsorption of CH_3Cl and CH_3I was recently investigated on Pd/SiO₂ by Fourier transform infrared spectroscopy (FTIR),

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which proved to be a very sensitive tool to follow the dissociation and reactions of these compounds (4).

The present paper deals with the study of the surface interaction of CH_2Cl_2 with the same Pd/SiO_2 catalyst. For comparison, some measurements have been also carried out on the adsorption of CH_2I_2 . The primary aim of the work is to examine the possibility of the generation of methylene, CH_2 , species and to determine its thermal stability and reactions. It is envisioned that the results obtained provide a better understanding of the catalytic reactions involving CH_2 intermediates. In addition, it is hoped that the results give useful information for the catalytic destruction of halogenated hydrocarbons, which is an important task for the cleaning of the environment.

As regards the adsorption of methylene halides on supported metals, we found no data in the literature. Several works have dealt, however, with the adsorption and decomposition of these compounds on metal surfaces under UHV conditions (2, 5-10).

2. EXPERIMENTAL

Pd/SiO₂ samples were prepared by incipient wetting of silica (Cabosil) with an aqueous solution of palladium chloride (Johnson-Matthey). For preparation triply distilled water was used. The Pd content was 10 wt.%. All materials used were of analytical grade. The purity of Cabosil SiO₂ was checked by inductively coupled plasma (ICP) spectroscopy. The following elements were detected: Zn, 0.00128%; Ni, 0.00076%; Fe, 0.00053%; and Co, 0.00002%. Tests for Mg, Al, Ca, Cr, Ba, Ti, Na, K, Li, Cu, and Cd were negative. After impregnation the samples were dried in air at 373 K. For IR studies the dried Pd/SiO₂ powder was pressed into self-supporting wafers (30 \times 10 mm, 10 mg/cm²). The pretreatments of the samples were performed in a vacuum IR cell and agreed with that applied in our previous work (4). Briefly, the samples were (a) heated (20 K/min) to 673 K under continuous evacuation, (b) oxidized with 100 Torr of O_2 (133.3 Pa) for 30 min at 673 K, (c) evacuated for 15 min, and (d) reduced in 100 Torr of H_2 for 60 min at 673 K. This temperature is sufficient to achieve a complete reduction. This was followed by degassing at the same temperature for 30 min and by cooling the sample to the temperature of the experiment.

 CH_2Cl_2 (Merck) and CH_2I_2 (Merck) were purified by fractional distillation and stored in a glass bulb. CH_2I_2 was protected against light.

Infrared spectra were recorded with a BIORAD (Digilab) FTIR spectrometer (FTS 7) with a wavenumber accuracy of ± 2 cm⁻¹. Typically 16 scans were registered. All subtractions of the spectra were taken without the use of a scaling factor (f = 1.0000). Mass spectrometric analysis was performed with the help of an MS 10 (AEI) mass spectrometer.

3. RESULTS

3.1. Adsorption of CH₂Cl₂

Figure 1 shows the infrared spectrum of gaseous CH₂Cl₂ (10 Torr). Absorption bands are listed in Table 1, where the literature data are also presented. Our gas-phase spectrum is consistent with that obtained formerly for CH₂Cl₂ gas (11, 12).

The spectrum obtained in the presence of 10% Pd/SiO₂ at 213 K showed spectral features different from those of

the CH_2Cl_2 gas spectrum registered at 300 K. The band at 3004 cm⁻¹ did not appear, but a new band at 3064 cm⁻¹ could be detected. A small shift of -2 cm⁻¹ in the position of $\nu_s(CH_2)$ occurred, and a very weak band at 2907 cm⁻¹ also appeared. More interestingly, a greater shift in the (CH_2) deformation mode (1464 cm⁻¹) ($\Delta\nu=-38$ cm⁻¹) was observed on the spectrum of adsorbed CH_2Cl_2 (Fig. 1). In response to CH_2Cl_2 adsorption the intensity of the silica OH band at 3744 cm⁻¹ decreased and a broad band centered at 3662 cm⁻¹ developed. Evacuation at 213 K caused only a slight attenuation of the absorption bands observed in the presence of gaseous CH_2Cl_2 .

Heating of the sample in vacuum to 243 K led to the complete elimination of the 3064 cm⁻¹ band (Fig. 2). Further heating of the sample under continuous evacuation to 263 K resulted in a small diminution of the 2984 and 2907 cm⁻¹ bands (Fig. 2). At and above 263 K new bands at 2922 and 2857 cm⁻¹ developed with the concomitant decrease of the bands at 2984 and 2907 cm⁻¹. Maximum intensities of the new bands were measured at 373 K, and the bands at 2984, 2922, and 2857 cm⁻¹ were detected up to 473 K.

Mass-spectrometric analysis of the gas phase during heating of the adsorbed layer showed the desorption of CH_2Cl_2 above 230 K. A slight decomposition of CH_2Cl_2 also occurred as indicated by the formation of C_2H_4 and HCl (Fig. 3A).

In subsequent measurements the Pd/SiO₂ sample was slowly heated in CH₂Cl₂ vapor from 133 to 293 K and the

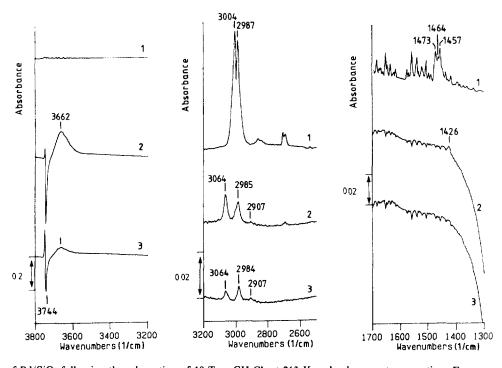


FIG. 1. Spectra of Pd/SiO₂ following the adsorption of 10 Torr CH_2Cl_2 at 213 K and subsequent evacuation. For comparison the gas-phase spectrum of CH_2Cl_2 is also shown. 1, CH_2Cl_2 gas at 300 K; 2, Pd/SiO_2 in the presence of CH_2Cl_2 at 213 K; 3, evacuation at 213 K after (2).

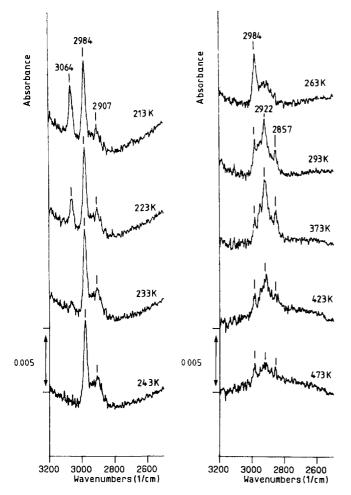


FIG. 2. Spectral changes conserved on heating the adsorbed layer on Pd/SiO_2 under continuous evacuation. CH_2Cl_2 (10 Torr) was adsorbed at 213 K.

spectra were registered at selected temperatures. With the increase of temperature, a significant change occurred in the OH frequency range: the new band at 3597–3660 cm⁻¹ gradually intensified and, at the same time, the OH band of SiO₂ at 3744 cm⁻¹ attenuated. This is illustrated in Fig. 4A, where the values of integrated absorbance at 3660 and 3744 cm⁻¹ are plotted. A maximum for the band at 3660 cm⁻¹ and a minimum for that at 3744 cm⁻¹ appeared at 223 K.

When the sample was kept in CH₂Cl₂ vapor at high temperature (300-573 K) for 10 min and the spectra were then recorded in the presence of CH₂Cl₂ at 300 K, no spectral features different from those attributed to gaseous CH₂Cl₂ were observed. However, after degassing of the sample at 300 K, weak absorption bands remained at 2961, 2925, and 2852 cm⁻¹. Their intensities markedly decreased with the rise of the temperature and they were not detectable after treating the catalyst with CH₂Cl₂ at

and above 473 K. No bands were seen in the frequency range 1300-1700 cm⁻¹.

Mass-spectrometric analysis of the gas phase showed that the decomposition of CH₂Cl₂ on Pd/SiO₂ proceeds above 350 K to produce HCl, C₂H₄, CH₄, and H₂O (Fig. 3B).

Similar measurements were performed with the silica support alone. In the frequency range of OH groups we observed the same changes as described for Pd/SiO₂. In this case the changes in the OH frequency range occurred in a narrower temperature range. The highest absorption for the 3660 cm⁻¹ band and the lowest absorption for the 3744 cm⁻¹ band were obtained at 213 K (Fig. 4). Adsorption of CH₂Cl₂ on SiO₂ at 215 K produced much weaker absorption bands than the Pd/SiO₂. No detectable absorption bands remained in the spectrum after degassing at 233–243 K. In the products desorbing between 200 and 350 K we identified CH₂Cl₂ and small amounts of HCl and C₂H₄.

3.2. Adsorption of CH_2I_2

Some measurements also have been performed with CH_2I_2 . Characteristic absorption bands for gaseous CH_2I_2 and CH_2I_2 adsorbed on Pd/SiO_2 are listed in Table 1.

When the sample was heated in the presence of CH_2I_2 from 213 K, a broad band centered at around 3630 cm⁻¹ was also observed, besides the band at 3744 cm⁻¹, characteristic for OH groups on the silica surface. The integrated absorption of this broad band showed a maximum at 266 K, and that of the 3744 cm⁻¹ band exhibited a minimum at the same temperature. This change is illustrated in Fig. 4. In the CH frequency ranges we observed spectral changes similar to those measured for CH_2Cl_2 . The absorption bands, however, were very weak, and it was difficult to enhance them. The main reason is that this compound has a very low vapor pressure. Application of higher pressures of CH_2I_2 required the heating of the CH_2I_2 reservoir, which led to appearance of iodine in gas phase indicating the decomposition of the compound.

4. DISCUSSION

4.1. Literature Survey of Surface Chemistry of CH₂-Containing Compounds

Relatively little information can be found in the literature on the chemistry of adsorbed CH_2X_2 (X, halogens) (6–9). In the study of the interaction of CH_2Cl_2 with evaporated Pd films it was observed that the C-Cl bond is ruptured before any C-H bond breakage occurs. Mass-spectrometric analysis revealed the formation of CH_4 and C_2H_4 at 273–373 K. On Pd(100), under UHV conditions at 300 K, the complete dissociation of CH_2Cl_2 to C, Cl, and H occurred (9). The dissociation of CH_2I_2 was observed at

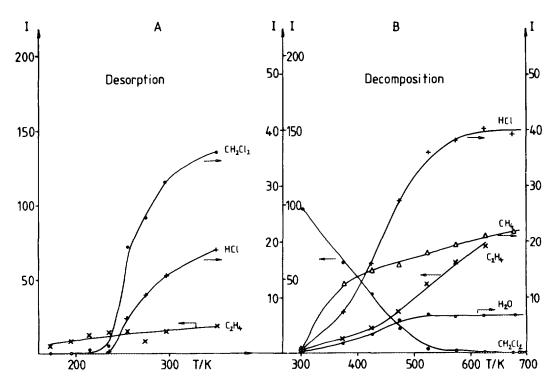


FIG. 3. Mass-spectrometric analysis of the gas phase during the heating of adsorbed CH₂Cl₂ (CH₂Cl₂ was adsorbed at 193 K and evacuated at the same temperature) (A) and during decomposition of CH₂Cl₂ (5 Torr) on Pd/SiO₂ at 300-700 K (B). The sample was kept at the selected temperature for 15 min before the temperature was raised.

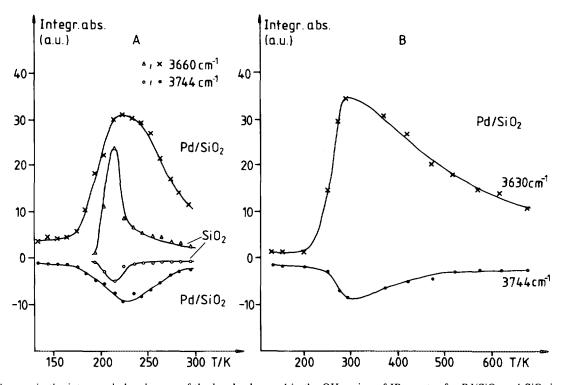


FIG. 4. Changes in the integrated absorbances of the bands observed in the OH region of IR spectra for Pd/SiO_2 and SiO_2 in the presence of CH_2Cl_2 (10 Torr) (A) and CH_2I_2 (1 Torr) (B) as a function of the adsorption temperature.

	$CH_2Cl_{2(g)}$		CH ₂ Cl ₂ /Pd/SiO ₂			CH ₂ I ₂ /Rh(111)	CH ₂ I ₂ /Pd/SiO ₂ at 213 K ^a
Assignment	(11, 12)	$CH_2Cl_{2(g)}^a$	at 213 K ^a	$CH_2I_{2(g)}$ (13)	$\mathrm{CH_2I_{2(g)}}^a$	(10)	
$\nu_{\rm as}({\rm CH_2})$	3045 (liquid)		3064 (liquid)	3047	3047	3030	3057
$\nu_s(\mathrm{CH}_2)$	3007 (R)	3004	2984	2970	2974	2940	2970
	2991 (P)	2987		2968			
$\delta(CH_2)$	1473 (R)	1473, 1464, 1457	1426	1343, 1353		1350	_
	1462 (P)						
CH2 wag	1275.1 (R)	1275					
	1268.1 (Q)						
	1260.6 (P)						
$\rho(CH_2)$	897.7	866		_		720	
				717			
$\nu_{\rm as}(\text{C-X}_2)$	763.5 (R)		_	573, 571			
	758.5 (Q)	-	_				
$\nu_s(C-X_2)$	727.5 (R)			487, 486	_		_
	707.5 (P)	_					

TABLE 1

Bands Characteristic for Gaseous and Adsorbed CH₂Cl₂ and CH₃I₂

submonolayer coverage on Pd(100) at 90 K (2). The primary products of dissociation, CH₂ and I, were identified by photoelectron spectroscopy (XPS and UPS). A marked enhancement of the dissociation proceeded following illumination of adsorbed layer at 90 K (2). The CH₂ reacted to form methane and ethylene at 160–230 K. Similar features have been observed on Rh(111) surface, with the difference that the extent of coupling of CH₂ species was much less than on Pd(100) (10).

4.2. Adsorption of CH₂Cl₂ on SiO₂

The changes in the OH region of the SiO₂ spectra show the important role of surface OH groups in the adsorption processes of methylene halides. In response to the adsorption of these molecules the intensity of the sharp band at 3744 cm⁻¹ (due to free OH groups on the silica surface) is reduced, and a broad absorption appears on the low wavenumber side of this band indicating the presence of H-bridge-bonded surface species. It is noteworthy that after elimination of this broad absorption, the intensity of the 3744 cm⁻¹ band never reached its original value. All these phenomena indicate that: (i) Si-OH groups are involved in the development of H-bridge-bonded CH_2X_2 species and (ii) surface OH groups of silica are consumed in the formation of desorption products. We may consider that CH_2X_2 molecules interact with the protons of vicinal OH groups of silica with one of the halide ends.

On heating the adsorbed layer the broad absorption disappears as a result of the molecular desorption of CH_2X_2

molecules (detected by MS). In addition, however, the elimination of HCl also occurs, as indicated by the presence of HCl in the desorbing product.

If the CH_2X_2 interacts with both halide ends then the elimination of HCl (or HI) is accompanied by the formation of adsorbed CH_2 species, which decomposes or dimerizes into ethylene. The fact that C_2H_4 was also detected in the desorbing products may support this reaction scheme. It should be mentioned that the lowest integrated absorption value for the 3744 cm⁻¹ band and the highest absorption for the broad spectral feature were experienced at the same temperature. This temperature was 213 K for CH_2Cl_2/SiO_2 and 266 K for CH_2I_2/SiO_2 systems (Fig. 4).

Note that we observed the same features following the adsorption and desorption of CH₃Cl on SiO₂ and Pd/SiO₂ surfaces (4). In that case the evolution of HCl and CH₄ was registered.

In the case of CH_2Cl_2 adsorption weak bands at 3064 and 2984 cm⁻¹ remained in the spectrum even after degassing the sample at 213 K. The 3064 cm⁻¹ band is close to the band attributed to liquid CH_2Cl_2 (Table 1). Therefore we assign these two bands to ν_{as} and ν_{s} of the liquid CH_2Cl_2 .

4.3. Adsorption of CH₂Cl₂ on Pd/SiO₂

Following the adsorption and evacuation of CH₂Cl₂ at 213 K, we observed the same spectral features as for pure

[&]quot; This work.

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Assignment	CH ₂ (ex CH ₂ CO) on Ru(001) (14)	CH ₂ (ex CH ₂ N ₂) on Ru(001) (15)	CH ₂ (ex CH ₂ CO) on Fe(110) (16)	CH ₂ (ex CH ₂ I ₂) on Rh(111) (10)
$\nu_a(CH_1)$	2945			2940
$\nu_s(CH_2)$	2870	2965	2970	
$\delta(CH_2)$	1295		1430	
CH, wag	1065	1155	1020	1190
τ(CH ₂)			930	
$\rho(CH_2)$	890	785	790	780
$\nu_s(M-C)$			650	650

TABLE 2

High Resolution Electron Energy Loss Frequencies (in cm⁻¹) of Adsorbed CH₂ Species

 SiO_2 . The difference is that the changes in the OH region occurred in a broader temperature range than SiO_2 .

As regards the effects of Pd on the further reactions of CH_2Cl_2 , we have to answer the following questions: (i) Are there any differences in the IR spectra of adsorbed CH_2Cl_2 on SiO_2 and Pd/SiO_2 ? (ii) Can we find any indication for the dissociation of CH_2Cl_2 over Pd and for the formation of CH_2 species? (iii) What are the stability and reaction products of CH_2 fragments on Pd?

To provide some general background, in Table 2 we have collected the vibrational characteristics of adsorbed CH₂ species produced on several metals by thermal dissociation of various CH₂-containing compounds. In Tables 3 and 4 data on the vibrations of adsorbed ethylene and ethylidyne (CCH₃), the possible products of CH₂ reactions, are presented for some relevant related systems.

From the comparison of the spectral data for the two samples, we can conclude that significant differences exist between SiO₂ and Pd/SiO₂. After the elimination of weakly adsorbed CH₂Cl₂ (disappearance of the band at 3064 cm⁻¹) from Pd/SiO₂ at 233–243 K, relatively intense bands remained in the spectra at 2985 and 2907 cm⁻¹, which are not detected, or hardly detected, on pure SiO₂. We may attribute these bands to chemisorbed CH₂Cl₂ on Pd, or to the CH_{2(a)} species formed in the dissociation of CH₂Cl₂. Taking into account that the 2907 cm⁻¹ wavenumber is too low to be assigned to the symmetric stretch

TABLE 3

Vibrational Frequencies (in cm⁻¹) of Low-Temperature
Adsorption Forms of Ethylene

Assignment	Pt/SiO ₂ (21, 26)	Pt/SiO ₂ (21, 26)	Pt/Al ₂ O ₃ (23)	Rh/Al ₂ O ₃ (23)	Rh/SiO ₂ (24)
$\nu_{\rm as}({\rm CH_2})$	_	_		3080	3011
$\nu_s(CH_2)$	3016	2922	2912	2966	2970
$\nu(CC)/\delta(CH_1)$	1496	[1428]	[1427]	1509	1508
$\delta(CH_2)/\nu(CC)$	_		_	1222	
Surface species	π	di- σ	di-σ	π	π

of CH₂Cl₂ (Table 1), the 2984 and 2907 cm⁻¹ bands are tentatively ascribed to the asymmetric and symmetric stretches of CH₂(a) species formed in the dissociation of CH₂Cl₂.

An alternative explanation is that the 2907 cm⁻¹ band is due to the vibration of ethylene formed in the dimerization of CH₂. However, we found no traces of a band at 1428–1509 cm⁻¹ (due to $\nu(CC)/\delta(CH_2)$) which would be decisive proof for the existence of ethylene on the surface.

Further spectral changes occurred above 263 K, when the 2907 cm⁻¹ band moved to 2922 cm⁻¹ and became more intense. At the same time a new band appeared at 2857 cm⁻¹. These spectral features correspond well to those of ethylidyne (Table 4). We tentatively assign these bands to the $\nu_{as}(CH_3)$ and $\nu_s(CH_3)$ vibrations of ethylidyne surface complex. In this temperature range we observed the desorption of ethylene, but found no IR spectral indications for the presence of adsorbed ethylene. This suggests that adsorbed ethylene could not be accumulated to a detectable extent on Pd/SiO₂ during the decomposition of CH₂Cl₂, and/or its transformation into other surface complexes is fast. Note that in this temperature range adsorbed ethylene (the di- σ -bonded species) readily transforms into ethylidyne on metal surfaces (28–30).

On summing up the above considerations and taking into account the results obtained for Pd(100) surface (2), we can account with the following steps for the decomposition of CH₂Cl₂ on Pd/SiO₂ catalyst:

$$CH_{2}Cl_{2} = CH_{2(a)} + 2 Cl_{(a)}$$

$$CH_{2(a)} = C_{(a)} + 2 H_{(a)}$$

$$CH_{2(a)} + 2 H_{(a)} = CH_{4(g)}$$

$$Cl_{(a)} + \frac{1}{2} H_{2} = HCl_{(g)}$$

$$2 CH_{2(a)} = \pi - C_{2}H_{4(a)}$$

$$\pi - C_{2}H_{4(a)} = C_{2}H_{4(g)}$$

$$\pi - C_{2}H_{4(a)} = di - \sigma - C_{2}H_{4(a)}$$

$$di - \sigma - C_{2}H_{4(a)} = CCH_{3(a)} + H_{(a)}.$$

), Pt/TiO,	D: /0:0			
(25)	Pt/SiO_2 (21)	Pt/SiO ₂ (26)	(CH ₃ C)Co ₃ (CO) ₉ (27)	Pd/Al ₂ O ₃ (23)
2920			2950	2931
	2880	2881	2890	2871
_			1420	1396
1335	1342	1342	1350	1331
1115		_	1130	_
	(25) 2920 — 1335	(25) (21) 2920 — 2880 — 1335 1342	(25) (21) (26) 2920 — — — 2880 2881 — — — — 1335 1342 1342	(25) (21) (26) (27) 2920 — — 2950 — 2880 2881 2890 — — — 1420 1335 1342 1342 1350

TABLE 4 Vibrational Frequencies (in cm $^{-1}$) Due to Ethylidyne (-CCH $_3$) Formed during C_3H_4 Adsorption

Note that the main product of the reactions of CH_2 species (produced by thermal- and photodissociation of CH_2I_2) on Pd(100) surface is ethylene (2). In the optimum case the ratio C_2H_4/CH_4 was 3.0-3.5. The high tendency of CH_2 for dimerization is in harmony with theoretical calculation, which showed that the activation energy of coupling of the species CH_2 on metal surfaces is only 6-9 kcal/mol (31).

In the brief study of the adsorption of CH_2I_2 on Pd/SiO_2 we observed spectral features that were in many respects similar to those measured for the adsorption of CH_2Cl_2 . Small shifts in the characteristic absorption bands of gaseous CH_2I_2 to higher wavenumbers were experienced following its adsorption (Table 2). Changes in the intensities of the absorption in the OH region clearly demonstrate that the surface OH groups are involved in the bonding of CH_2I_2 on the surface, similarly as proposed for CH_2Cl_2 adsorption (subsection 4.1.).

Adsorbed CH_2I_2 is characterized by absorption bands at 3057 and 2970 cm⁻¹ in the high-frequency region. On the basis of the data collected in Table 1, these bands are assigned to the asymmetric and symmetric stretches of adsorbed CH_2I_2 . Spectra of the annealed system qualitatively agreed with those observed for the CH_2Cl_2 -Pd/SiO₂ system. Absorption bands were, however, very weak and prevented a more detailed analysis. Nevertheless, they indicate that the dissociation of CH_2I_2 also occurs on supported Pd to produce a CH_2 species, which probably undergoes similar reactions as observed following CH_2I_2 adsorption on Pd(100) surface (2) or following CH_2Cl_2 adsorption on Pd/SiO₂.

5. CONCLUSIONS

- (i) Methylene chloride and iodide interact with OH groups of silica to form H-bridge-bonded species.
- (ii) The dissociation of CH₂Cl₂ was observed on Pd/SiO₂ at 233-243 K, as indicated by the development of absorption bands at 2984 and 2907 cm⁻¹.
- (iii) The CH_2 dimerized into C_2H_4 which partly desorbed and partly transformed into ethylidyne.

- (iv) Ethylidyne is characterized by absorption bands at 2922 and 2857 cm⁻¹.
- (v) CH_2Cl_2 decomposes on Pd/SiO_2 at a measurable rate above 350 K to give C_2H_4 , CH_4 , HCl, and H_2O .
- (vi) CH₂I₂, due its lower vapor pressure, is a less suitable compound to produce CH₂ species on supported Pd.

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